

## Model : CRESBOX

Semi-automatic 4 point probe sheet resistance/resistivity measurement system



**High performance & Small foot print**

**Programmable & arbitrary pattern for round & square shape**

### Features

- Multi-points measurement and Mapping display
  - 2-D map / 3-D map graphic display
- Multipoint pattern measurement is programmed (maximum 1225 points) and random pattern is programmable by operator.
- Film thickness conversion function from sheet resistance
- Measurement data base link with Excel via CSV format file
- Software language can be switched in English / Japanese by operator
- Complies with the following ASTM & JIS
  - <JIS> JIS H 0602-1995, JIS K 7194-1994
  - <ASTM> ASTM F 84-99(SEMI MF84),  
ASTM F 374-00a, ASTM F 390-11,  
ASTM F 1529-97

### Applications

- Semiconductor materials, Solar-cell materials (Silicon, Polysilicon, SiC etc)
- New materials, functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials, Ion-implantation sample
- Others (\*Please contact us for details)

### Sample Sizes

Size : ~ 8 inch, ~ 156x156mm

Thickness : ~ 2mm

### Measurement Range

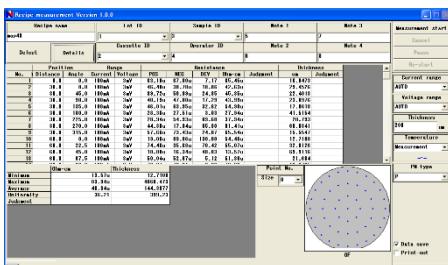
Test Item	Measurement Range
V/I Ratio	1m ~ 3M ohm
Sheet resistance	5m ~ 10M ohm/sq
Resistivity(Slice:100~2000μm)	1m ~ 300k ohm.cm

A global leading company for resistivity measurement system.



## Software Function

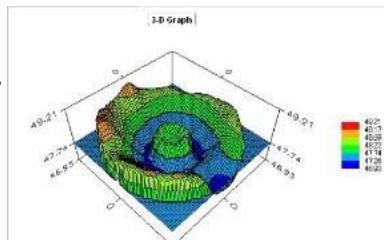
- Measurement result can be displayed by 2-D / 3-D map graphic.
- Mapping graphic can be saved by JPEG file.
- SPC Chart display function.



Software : Main



SPC Chart display



3-D map graphic (Round)



3-D map graphic (Square)

## Measurement Accuracy / Repeatability

### Measurement Accuracy

$$\%BIAS < \pm 1\%$$

$$\%BIAS = \frac{\bar{X} \boxtimes NIST\text{guaranteed value}}{NIST\text{guaranteed value}} \times 100[\%]$$

$\bar{X}$  ----- Average of same point x 10times measurement( $23^{\circ}\text{C}$ )

### Measurement Repeatability

$$CV \leq 0.7\%$$

$$CV = \frac{\sigma}{\bar{X}} \times 100[\%]$$

$\sigma$  ----- Standard deviation of same point

x 10times measurement( $23^{\circ}\text{C}$ )

$\bar{X}$  ----- Average of same point x 10times measurement( $23^{\circ}\text{C}$ )

## Throughput (Tact time)

Points	Tacttime	Time / Point
1	16s ( $\pm 3\text{s}$ )	16s
5(+)	25s ( $\pm 3\text{s}$ )	5s
5(-)	25s ( $\pm 3\text{s}$ )	5s
9(+)	34s ( $\pm 3\text{s}$ )	3.8s
17	48s ( $\pm 3\text{s}$ )	2.7s
49	110s ( $\pm 3\text{s}$ )	1.9s

\*Throughput will change by setting conditions, resistance value and the sample surface state.

\*Please contact us for more details.

\*The customers are always welcome to do Demo measurement.

\*Specification subject to change without notice.



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